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Patent Application
Preliminary Amendment
Docket No. PI-128

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s) : Hyun Soo Roh; Tae Won Park; Kill Sung Lee; In Kyung Lee

Docket No. : PI-128

For : Slurry Composition for Secondary Polishing of Silicon Wafer

Mail Stop PCT

Commissioner for Patents

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PRELIMINARY AMENDMENT

This application is a National Stage Application of International Application Number PCT/KR2003/01532. Please amend the above-identified patent application as follows:

Amendments to the Specification begin on page 2 of this paper.

Remarks follow the amendment sections of this paper.